

Captive Spin Chucks

For Cee® Equipment

The Cee® Equipment product portfolio offers over 8,000 spin chuck designs that can accommodate a wide range of substrate sizes, shapes, or materials. In-house mechanical engineers are available to modify existing concepts or create custom spin chuck designs, per specific customer requests.

Serving the Semiconductor Industry Since 1987

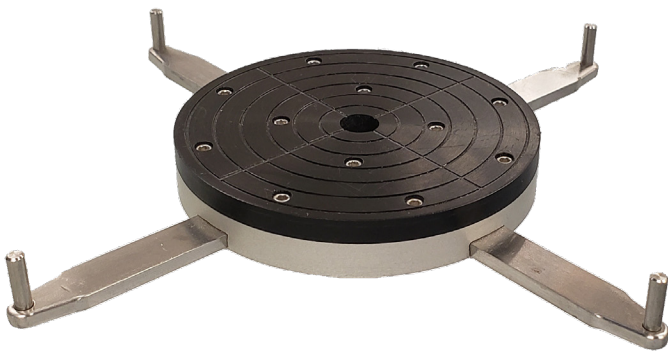


CHUCK DESIGN

- Each captive spin chuck is custom-made to the exact specifications of the customer's substrate.
- Available materials include Delrin®, Kynar® (PVDF), Teflon® (PTFE), Stainless Steel, PEEK, and Anodized Aluminum
- The support pins are lower than the top of the substrate to allow the coated material to flow off
- Precisely machined for exact fit and flatness

APPLICATION NOTES

- Used for developing and cleaning application



BENEFITS

- Safely secures heavier and thicker substrates than standard vacuum chuck.
- Provides auto-centering function and additional lateral support for the substrate.
- Genuine Cee® spin chucks guarantee optimal performance

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